Application No. 10/694,474

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Kathryn Marley

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of Inventors:

Christophe Pierrat et al.

Application No. 10/694,474

Filed: 27 October 2003

Title: Mask Data Preparation

**CUSTOMER NO. 22470** 

Group Art Unit: unknown

Examiner: unknown

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.56

Sir:

It is requested that the information identified in this statement be considered by the Examiner and made of record in the above-identified application. This statement is not intended to represent that a search has been made or that the information cited in the statement is, or is considered to be, material to patentability as defined in 37 C.F.R. 1.56.

Enclosed with this statement is a Form PTO-SB/08. The Examiner is requested to initial the form and return it to the undersigned in accordance with M.P.E.P. 609.

Also enclosed with this statement is a copy of each cited document as required by 37 C.F.R. 1.98. The exception to this, in accordance with the 05 August 2003 Official Gazette Notice in which the USPTO waives the requirement for submitting copies of U.S. Patent and Publications for cases filed after 30 June 2003, is that copies of U.S. Patent documents and copies of U.S. Patent publications are not being submitted.

This statement should be considered under 37 C.F.R. 1.97(b) because it is being filed within three months of the filing date of an application other than a continued prosecution application under 37 C.F.R. 1.53(d).

Fee Authorization. The Commissioner is hereby authorized to charge underpayment of any additional fees or credit any overpayment associated with this communication to Deposit Account No. 50-0869 (FTIS 1004-1). A copy of this authorization is enclosed.

Respectfully submitted,

HAYNES BEFFEL & WOLFELD LLP

Date: 10 No 12003

y: \_\_\_\_\_\_ Rea No. 20.84

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## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1 of

Complete If Known					
Application Number	10/694,474				
Filing Date	27 October 2003				
First Named Inventor	Christophe Pierrat et al.				
Group Art Unit					
Examiner Name					
Attorney Docket Number	FTIS 1004-1				

	U.S. PATENT DOCUMENTS								
Examiner Initials*	Cite No.1	U.S. Patent Number	Control   Code   Code	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear			
	A1	6,081,65	8	Rieger et al.	06-27-2000				
	A2								
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	FOREIGN PATENT DOCUMENTS											
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initials*	No.1	Office <sup>3</sup>	Number <sup>4</sup>	Kind Code <sup>5</sup> ( <i>if known</i> )	Applicant of Cited Document	Cited Document MM-DD-YYYY	Passages or Relevant Figures Appear	Tβ				
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<sup>&</sup>lt;sup>1</sup> Unique citation designation number. <sup>2</sup> See attached Kinds of U.S. Patent Documents. <sup>3</sup> Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). <sup>4</sup> For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. <sup>5</sup> Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. <sup>6</sup> Applicant is to place a check mark here if English language Translation is attached.



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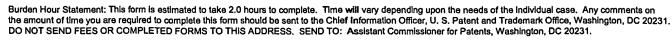
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	OTHER PRIOR ART NON PATENT LITERATURE DOCUMENTS							
Examiner Initials*	Cite No.1							
	C1	BRUNNER TIMOTHY A., et al., "Optical/Laser Microlithography VIII," SPIE, Vol. 2440, 301-312.						
	C2	GAROFALO, J., et al., "Automatic Proximity Correction for 0.35Fm I-Line Photolithography," IEEE, Numerical Modeling of Processes and Devices for Integrated Circuits, 1994. NUPAD V., International Workshop on 5-6 Jun 1994, 92-94.						
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•	C7	TORRES, J.A., et al., "Contrast-Based Assist Feature Optimization," Deep Submicron Technical Publication, May 2002, Mentor Graphics, 8 pages.						

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<sup>&</sup>lt;sup>1</sup> Unique citation designation number. <sup>2</sup> Applicant is to place a check mark here if English language Translation is attached.



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